



# EIR-3000 & EIR-2200

## FTIR FOR THICK DIELECTRIC MONITORING

FTIR using model based analysis and absolute reflectance for superior thickness and dopant measurement accuracy and reliability



SEMILAB EIR is the ultimate choice for thick dielectric monitoring such as BPSG, FSG, SiNx:H. The EIR has the unique ability to measure in reflection mode, like other conventional optical tools such as ellipsometer or reflectometer, with the benefit of simplifying requirements and conditions for measurement.

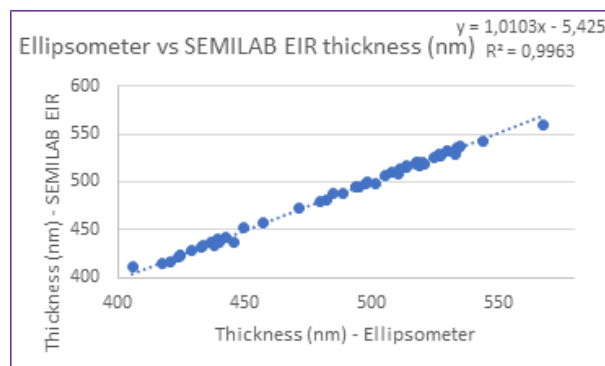
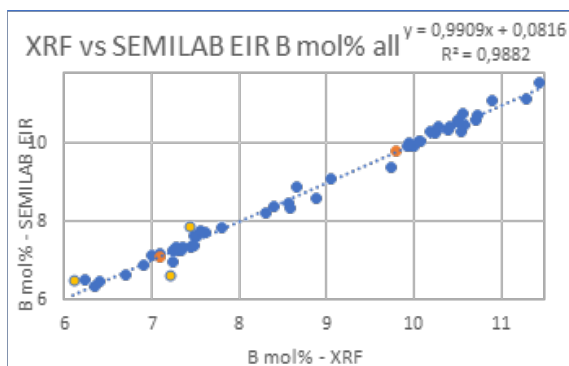


## Facts (Transmission Tools)

- FTIR is used for thick dielectric composition monitoring
  - Non-destructive
  - Uses monitor wafers with strong requirements
    - High sensitivity
    - Back side polish

## Benefits (Reflection Measurements)

- No requirement on backside wafer finishing
  - Wafer to be etched or polished
- No requirement on on wafer resistivity
  - Variation included in calibration
- Ability to use production wafers (same substrate)



This material is for information purposes only. Equipment acceptance is based on contracted specifications.

